CLAIMS

What is claimed is:

- A method, comprising:
 forming an electrically conductive interconnect on at least a part of an insulating surface on a substrate; and
 growing at least one fiber that is coupled to the electrically conductive interconnect.
- 2. The method of claim 1, wherein the at least one fiber is grown by DC plasma enhanced chemical vapor deposition.
- 3. The method of claim 1, wherein growing includes growing at least one carbon nanofiber.
- 4. The method of claim 1, wherein growing includes growing a plurality of substantially vertically aligned carbon nanofibers.
- 5. The method of claim 1, wherein growing includes coupling a catalyst to the electrically conductive interconnect before growing.
- 6. The method of claim 5, wherein the catalyst includes at least one metal selected from the group consisting of nickel, iron and cobalt.
- 7. The method of claim 5, further comprising removing the catalyst after growing.
- 8. The method of claim 1, wherein the substrate includes at least one member selected from the group consisting of silicon, quartz, sapphire and magnesia.
- 9. The method of claim 1, wherein the electrically conductive interconnect includes at least one refractory metal selected from the group consisting of W, Mo, Ta and Nb.

- 10. The method of claim 1, further comprising electrochemically passivating at least one member selected from the group consisting of at least a portion of a surface of the electrically conductive interconnect and at least a portion of a surface of the at least one fiber.
- 11. The method of claim 10, wherein electrochemically passivating includes depositing a dielectric layer including at least one member selected from the group consisting of SiO_2 , Si_3N_4 and a polymer.
- 12. The method of claim 10, wherein a tip of the at least one fiber is not passivated.
- 13. The method of claim 1, further comprising providing a buffer between the at least one fiber and the electrically conductive interconnect.
- 14. The method of claim 13, wherein the buffer includes at least one substance selected from the group consisting of Ti, W, Mo and titanium nitride.
- 15. The method of claim 14, wherein growing includes coupling a catalyst to the buffer before growing.
- 16. The method of claim 15, further comprising removing the catalyst after growing.
- 17. The method of claim 1, further comprising patterning the electrically conductive interconnect wherein the at least one fiber includes a plurality of fibers that are individually electrically addressable via the electrically conductive interconnect.
- 18. An apparatus made by the method of claim 1.
- 19. An assembly, comprising an article of manufacture made by the method of claim 1.
- 20. An apparatus, comprising:

an electrically conductive interconnect formed on at least a part of an insulating surface on a substrate; and at least one fiber coupled to the electrically conductive interconnect.

- 21. The apparatus of claim 20, wherein the at least one fiber includes at least one carbon nanofiber.
- 22. The apparatus of claim 21, wherein the at least one carbon nanofiber includes a plurality of substantially vertically aligned carbon nanofibers.
- 23. The apparatus of claim 20, further comprising a catalyst coupled to the at least one fiber.
- 24. The apparatus of claim 23, wherein the catalyst includes at least one metal selected from the group consisting of nickel, iron and cobalt.
- 25. The apparatus of claim 20, further comprising the substrate, wherein the substrate includes at least one member selected from the group consisting of silicon, quartz, sapphire and magnesia.
- 26. The apparatus of claim 20, further comprising the substrate, wherein the substrate is substantially optically transmissive.
- 27. The apparatus of claim 20, wherein the electrically conductive interconnect includes at least one refractory metal selected from the group consisting of W, Mo, Ta and Nb.
- 28. The apparatus of claim 20, further comprising an electrochemical passivator coupled to at least one member selected from the group consisting of at least a portion of a surface of the electrically conductive interconnect and at least a portion of a surface of the at least one fiber.

- 29. The apparatus of claim 28, wherein the electrochemical passivator includes a dielectric layer including at least one member selected from the group consisting of SiO₂, Si₃N₄ and a polymer.
- 30. The apparatus of claim 28, wherein a tip of the at least one fiber is not passivated.
- 31. The apparatus of claim 20, further comprising a buffer between the at least one fiber and the electrically conductive interconnect.
- 32. The apparatus of claim 31, wherein the buffer includes at least one substance selected from the group consisting of Ti, W, Mo and titanium nitride.
- 33. The apparatus of claim 20, wherein the at least one fiber includes a plurality of fibers that are individually electrically addressable via the electrically conductive interconnect.
- 34. The apparatus of claim 20, further comprising a parallel lead for active capacitance cancellation coupled to the electrically conductive interconnect.
- 35. A biosensor, comprising the apparatus of claim 20.
- 36. A field emitting array, comprising the apparatus of claim 20.
- 37. A kit, comprising:
 - a substrate having an insulating surface;
 - an electrically conductive interconnect formed on at least a part of the insulating surface; and
 - at least one fiber coupled to the electrically conductive interconnect.
- 38. The kit of claim 37, further comprising instructions.